



nSpec® Macro

nSpec[®] Macro

Standalone Macro Inspection



Nanotronics provides a full range of solutions for obtaining rapid results for your specific wafer inspection requirements.

The nSpec[®] Macro system is designed for inspection of bare or patterned wafers up to 200mm. The minimum defect resolution ranges from 50 to 100 microns, contingent on field of view or wafer size.

The compact system automatically captures and analyzes images to detect and quantify defects and features of interest.

The nSpec[®] Macro system provides full sample illumination or the ability to individually modify the LEDs to adjust the intensity, color, and location of illumination for complete flexibility.

Features:

- Fully Standalone
- Multi-tool shareable jobs
- Basic analysis with tunable parameters
- Sliding sample stage for easy loading
- Single pushbutton operation

SYSTEM

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Weight

15 kg

Dimension (W x D x H)

35 cm x 41 cm x 48 cm

Power Supply

Output: 24VDC, 10A

Input: 100-240VAC, 50/60Hz,

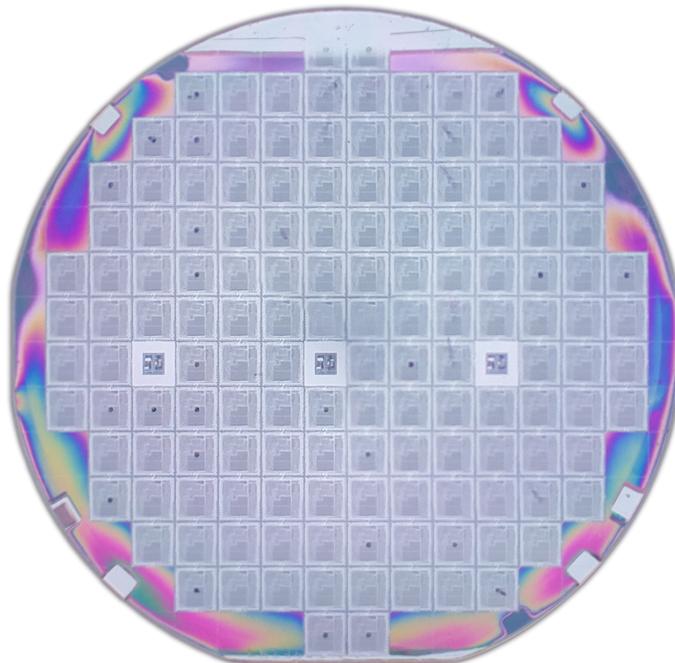
1.0 - 2.0A

SAMPLE SIZES

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Standard Sample Sizes

50, 75, 100, 150, or 200 mm



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